

EX. Amdt.

**Amendments to the Claims:**

This listing of claims will replace all prior versions, and listings, of claims in the application:

**Listing of Claims:**

1. <sup>conceded</sup>  
~~(Withdrawn)~~ A method of correcting defects of pattern film on a surface of a substrate, comprising the steps of:
  - holding the substrate with the surface facing downward;
  - blowing, by way of a gas window in a direction towards the surface of the substrate, material gas for forming pattern film to the surface; and
  - irradiating laser light upward at a white defect on the surface to form pattern film over the white defect.
2. <sup>conceded</sup>  
~~(Withdrawn)~~ The method claimed in claim 1, further comprising the steps of:
  - irradiating laser light upward at a black defect on the surface; and
  - vaporizing unnecessary part of pattern film in order to correct the black defect.
3. <sup>conceded</sup>  
~~(Withdrawn)~~ The method claimed in claim 1, further comprising the steps of:
  - blowing oxygen gas to the surface;
  - irradiating first laser light upward to unnecessary part of pattern film on the surface in order to oxidize the top layer of the part;
  - irradiating second laser light upward to the oxidized top layer in order to peel the oxidized top layer off; and
  - repeating the steps of irradiating first and second laser light in order to eliminate the unnecessary part of pattern film.
4. <sup>conceded</sup>  
~~(Withdrawn)~~ The method claimed in claim 1, wherein:

the step of blowing further blows purge gas, which prevents a window for conducting laser light from clouding, and carrier gas, which is included in CVD gas for carrying material gas; and

the main component of the purge and carrier gases is helium gas.

*conceded*  
5. (~~Withdrawn~~) The method claimed in claim 1, wherein the substrate is sucked in order to be held at the step of holding.

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6. (Currently Amended) A device for correcting defects of pattern film on a surface of a substrate, comprising:

a holder for holding the substrate with the surface facing downward;

a laser irradiator for irradiating laser light upward at a white defect on the surface; and

a gas window for blowing material gas on the surface and conducting laser light from the laser irradiator through the gas window to the white defect in order to form pattern film over the white defect,

wherein the laser irradiator comprises a first laser source for irradiating first laser light for vaporizing pattern film, and a second laser source for irradiating second laser light for laser CVD, and

wherein the holder sucks the substrate in order to hold the substrate,

wherein the gas window comprises:

a gas circulatory unit for providing gases to the gas window;

a flat lower window for receiving laser light;

a round groove;

a laser irradiating hole provided between the round groove and the flat lower window;

a first opening provided closer to the flat lower window than the laser irradiating hole, the first opening providing purge gas from the gas circulatory unit into the gas window;

a second opening provided closer to the laser irradiating hole than the flat lower window, the second opening providing material gas from the gas circulatory unit into the gas window; and

a third opening provided adjacent to the round groove, the third opening sucking the purge gas out of the gas window.

7. (Original) The device claimed in claim 6, further comprising an optical unit for observing pattern film on the substrate.

8. (Previously Presented) The device claimed in claim 7, wherein the substrate is permeable to light, further comprising a penetrating light source for irradiating light through the substrate to the lower surface of the substrate in order to illuminate the lower surface.

9. (Previously Presented) The device claimed in claim 8, further comprising:

a sucking unit having a top cover permeable to light;

wherein the penetrating light source comprises a lens that is designed to compensate the distortion of the lens with reference to a total thickness of the cover and the substrate.

10. (Previously Presented) The device claimed in claim 6, wherein the first laser light is irradiated through the gas window at black defects in order to vaporize the black defects; and

the second laser light is irradiated through the gas window at white defects with material gas in order to form film over the white defects.

11. (Previously Presented) The device claimed in claim 6, wherein:  
the gas window blows purge gas, which prevents a window for conducting laser light from clouding, and carrier gas, which is included in CVD

gas for carrying material gas; and

a main component of the purge and carrier gases is helium gas.

12. (Canceled).

13. (Previously Presented) The device claimed in claim 6, wherein the gas window is provided beneath the substrate and blows the material gas upwards towards the surface of the substrate.

14. (Currently Amended) The device claimed in claim 7, further comprising:

an object lens provided between the gas window and the optical unit,

wherein the gas window comprises:

~~a flat lower window for receiving laser light through the object lens;~~

a conical-shaped upper window,

wherein a conical-shaped cavity is provided between the flat lower window and the conical-shaped upper window.

15. (Currently Amended) The device claimed in claim 14, wherein ~~the gas window further comprises:~~

a round groove is provided directly beneath the conical-shaped upper window; ~~and~~

~~a laser irradiating hole provided between the round groove and the flat lower window.~~

16. (Canceled).

17. (Currently Amended) The device claimed in claim ~~46~~ 6, wherein the first and second openings are provided on opposite sides of the gas window.

18. (Previously Presented) The device claimed in claim 9, wherein the sucking unit comprises:

a sucking mount; and

a groove fitted around an inside of the sucking mount underneath the top cover; and

an airtight ring embedded in the groove so as to maintain an airtight space between the sucking unit and the substrate.

19. (Currently Amended) The device claimed in claim 18, further comprising:

a pump;

a pressure sensor; and

a tube connecting the pump and the pressure sensor,

wherein the sucking unit further comprises:

an opening for receiving the tube,

wherein the pump sucks out air in a space between the sucking unit and the substrate, in order to adhere the sucking unit to the substrate.

20. (Previously Presented) The device claimed in claim 15, wherein the laser irradiating hole is smaller in size than the flat lower window.

21. (New) The device claimed in claim 6, wherein the second opening is provided on one side of the laser irradiating hole, the second opening providing material gas directly into the laser irradiating hole, and

wherein the third opening is provided against one end of the round groove, the third opening sucking the purge gas out of the gas window by way of a sucking force applied to the round groove.